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IT-4-O-1437 Advancements in Integrated Micro-XRF in the SEM

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In recent years, small x-ray tubes have been modified for mounting on Scanning Electron Microscopes. There have been two main types: low-power miniature tubes mounted re-entrantly within the SEM [1], and higher-power tubes with integrated x-ray optics to produce smaller beam spots at the sample, yet with intensities high enough for routine analytical work [1,2]. This addition allows samples to be analyzed both by X-Ray Fluorescence (XRF), and by the electron beam (SEM-EDS), as illustrated by the two spectra in FIG. 1.

Both techniques can be used independently or together by taking sequential e-beam and x-ray excited spectra. Quantitative analysis using this combined approach was first shown at the IMC16 conference in Sapporo [3]. This approach uses the advantage of e-beam excitation for lighter elements below 2.0 keV, and the more-efficient XRF excitation for x-ray lines above 2.0 keV. Micro-XRF with X-Y stage scanning can be used to collect x-ray elemental maps similar to those collected with e-beams, except the stage is moved versus scanning of the beam. This Micro-XRF mapping method has been proposed for some time [e.g.4], and was first commercially demonstrated in 1986 [5]. It is possible to collect e-beam and x-ray excited maps simultaneously for combined qualitative x-ray elemental mapping.

Currently 40 μ m and 10 μ m x-ray beam spot sizes are available inside the SEM. The 10 μ m beam has shown count rates that exceed 2000cps on steel. Future expectations are of even smaller excitation areas, with "useful" x-ray count rates. To create a smaller spot the polycapillary optic needs to be more tightly focussed. This means that the Focal (working) Distance (FD) of the XRF source must be shorter. For example, for a 40 μ m spot, an FD of 11 mm is typical. With a 10 μ m excitation spot, an FD of about 4.5 mm is required, making the integration of the x-ray beam a bit more of a challenge (FIG. 2).

It is now possible to use primary filters (thin foils) in front of the x-ray source. Using an automated filter wheel, allows in situ tuning of the x-ray source spectrum [e.g. 4], with improved elemental detection limits. An automated filter wheel between the x-ray source and sample provides comparable capabilities to those in benchtop XRF. FIG. 3 shows a comparison of unfiltered and filtered spectra, showing how the overall "shape" can be varied to optimize sensitivities and peak-to-background ratios.

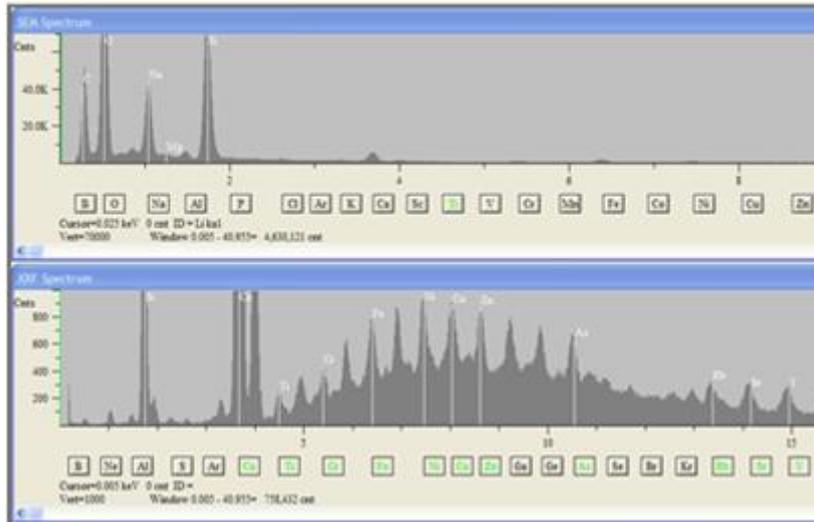


Fig. 1: EDS (top) and Micro-XRF (bottom) spectra of NIST SRM 610

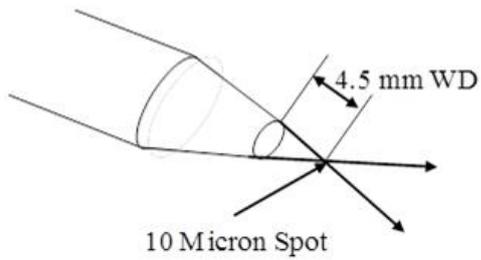


Fig. 2: Illustrates Focal Point and Working Distance

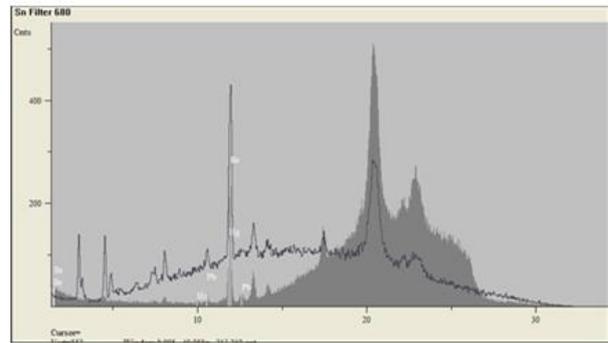


Fig. 3: Filtered Micro-XRF in SEM Spectrum